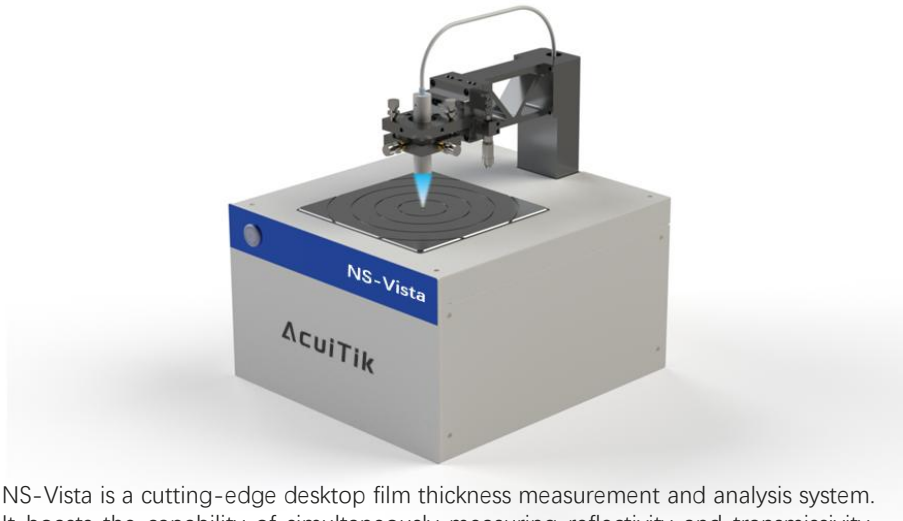




Film Thickness Measurement System **NanoSense**

NS-Vista (Reflection & Transmission Dual Channels)



NS-Vista is a cutting-edge desktop film thickness measurement and analysis system. It boasts the capability of simultaneously measuring reflectivity and transmissivity, making it extremely powerful for measuring specimens with both high and low reflectivity. Furthermore, the ***Vista Learning*** algorithm is specially designed for thickness measurement of very rough and thick surfaces. The spot size of the reflection channel can be easily adjusted from 1.5 millimeters down to 0.2 millimeters, which significantly expands the scope of thickness measurement applications. As a desktop equipment, NS-Vista represents the pinnacle of advanced technology in its field.

NS-Vista Features

- **Dual-channel design for simultaneous reflectivity and transmissivity measurement.**
- **Capable of measuring both high- and low- reflectivity materials.**
- **Dynamic adjustable spot size with a broad range.**
- **Vista Learning algorithm tailored for rough and thick materials.**